

Electronic Supplementary Information for

Effects of Ga doping and hollow structure on the band-structures and photovoltaic properties of SnO₂ photoanode dye-sensitized solar cells

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The Fermi level of the photoanode in a DSSC is an important parameter because the difference between the red-ox potential in the quasi-Fermi level of the anode and the electrolyte determines the V_{oc} of the DSSCs. Flat band potentials (E_{fb}) can be obtained from the intercept on the potential axis of Mott-Schottky plots using the equation

$$\frac{1}{C^2} = \left(\frac{2}{A^2 e \epsilon \epsilon_0 N_D} \right) \left(E - E_{fb} - \frac{kT}{e} \right),$$

where k the Boltzmann constant, T the absolute temperature, ϵ the dielectric constant of the SnO_2 layer, ϵ_0 the vacuum permittivity, e the electron charge, C represents the capacitance of the space charge region, N_D the donor density, E the applied potential, E_{fb} the flat band potential, and A is the active surface. As shown in Figure S1, the Mott-Schottky plots for the SnO_2 , $\text{Sn}_{0.99}\text{Ga}_{0.01}\text{O}_2$, $\text{Sn}_{0.97}\text{Ga}_{0.03}\text{O}_2$, $\text{Sn}_{0.95}\text{Ga}_{0.05}\text{O}_2$ films at 1000Hz in the dark provided values of E_{fb} of 0.095, 0.016, -0.133, and -0.290 V (vs. SCE).

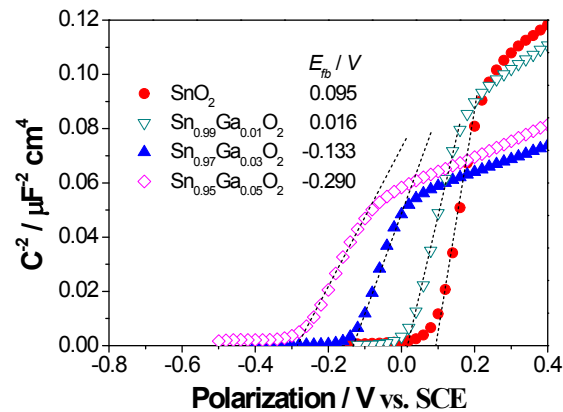


Fig. S1. Mott-Schottky plots of the SnO_2 and the Ga-doped SnO_2 films prepared on FTO substrates.

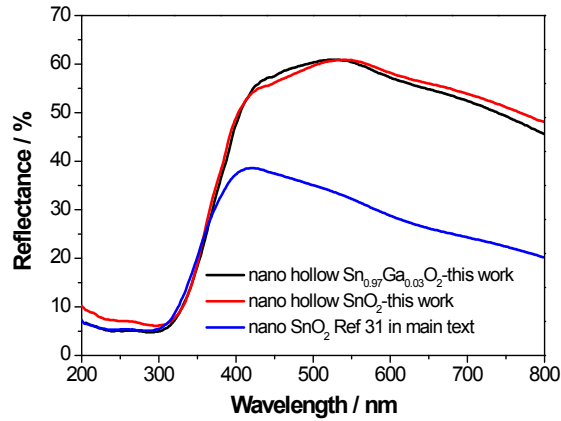


Fig. S2. Diffuse reflectance spectra of the photoelectrodes with nano SnO₂, nano hollow SnO₂ and nano hollow Sn_{0.97}Ga_{0.03}O₂. The reflectance of the SnO₂ and Sn_{0.97}Ga_{0.03}O₂ hollow sphere films are much higher than that of the SnO₂ nanocrystalline films, indicating that the particles in the hollow sphere film have a higher light scattering ability than those in the SnO₂ nanocrystalline film.

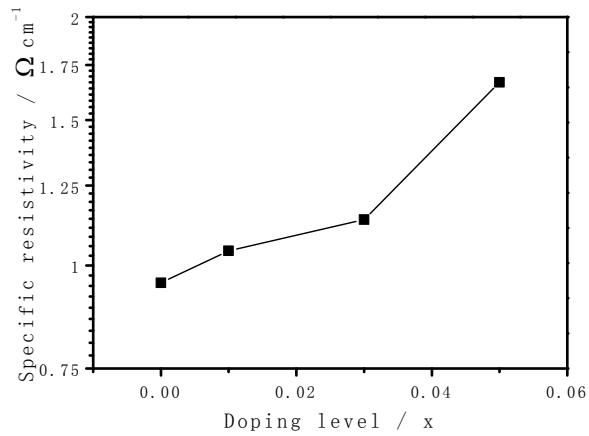


Fig. S3. Specific resistivity as a function of doping level for Sn_{1-x}Ga_xO₂ films.

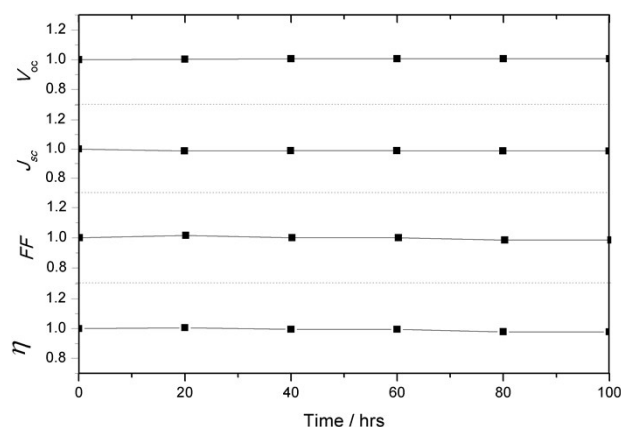


Fig. S4. Normalized device performance under constant illumination for 100h measured in air (DSSCs based on $\text{Sn}_{0.97}\text{Ga}_{0.03}\text{O}_2/\text{TiCl}_4$). The values plotted in **Fig. S4.** are the averages over five samples. After 100 hrs, the conversion efficiency of DSSC is maintained at about 100% to the initial one.

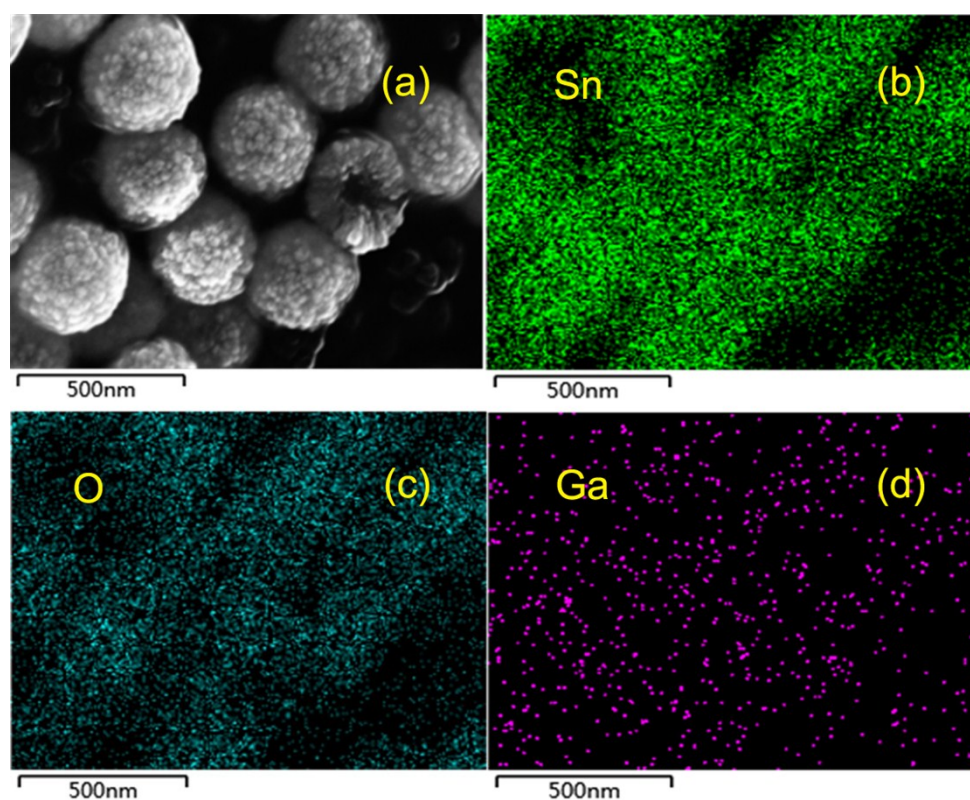


Fig. S5. (a) SEM image of the $\text{Sn}_{0.97}\text{Ga}_{0.03}\text{O}_2$ synthesized from chemicals. (b)-(d) Elemental mapping performed from the SEM image (a). The elements (Sn, O, Ga) are uniformly distributed in the sample, indicative of the high homogeneity of the $\text{Sn}_{0.97}\text{Ga}_{0.03}\text{O}_2$ particles.

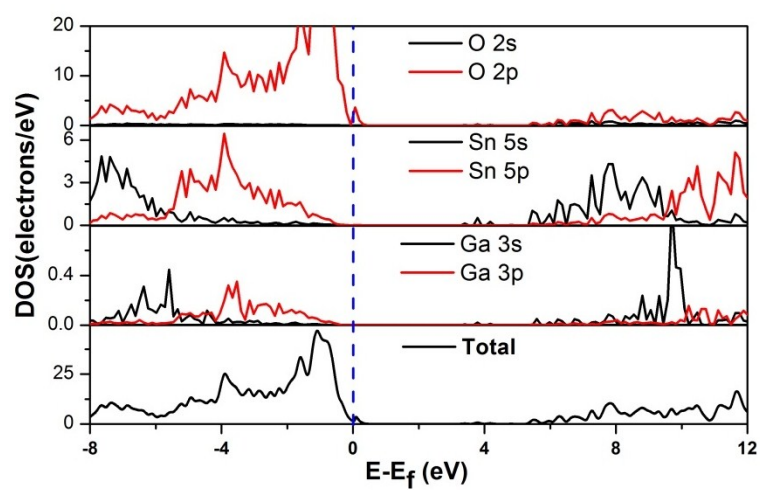


Figure S6. Calculated total and orbital resolved densities of states for the pure SnO₂ and 6.25% Ga doped SnO₂. The Fermi level is set to zero.

Table S1 The reported high values of η obtained in the DSSCs based on different SnO₂ photoanode structures.

Ref.	Morphology or structure	Diameter	Synthetic method or manufacturer	Film thickness	η (%) (no surface treatment)	η (%) (after surface treatment) ^a
1	SnO ₂ nanoparticles	3-5 nm	Alfa Aesar	10 μ m	1.74	MgO/7.21
2	SnO ₂ nanowire	20-200nm	reactive vapor transport	25-30 μ m	2.1	TiCl ₄ /4.1
3	SnO ₂ hollow microspheres	1-2 μ m	hydrothermal	10 μ m	1.4	TiCl ₄ /5.65
4	SnO ₂ nanoflower	1 μ m	hydrothermal	8-10 μ m	3.00	TiCl ₄ /6.78
5	SnO ₂ nanoparticles	15 nm	Alfa Aesar	---	1.7	CaCO ₃ /5.4
6	SnO ₂ nanopowder	<100 nm	Sigma-Aldrich	8 μ m	3.65	MgO/6.40
7	SnO ₂ nanotube	110 nm	electrospinning	13 μ m	0.99	TiCl ₄ /5.11
8	SnO ₂ hollow nanospheres	200 nm	hydrothermal	---	0.86	TiCl ₄ /6.02
9	SnO ₂ octahedra	0.5-1.8 μ m	sonochemical	13.2 μ m	---	TiCl ₄ /6.8
10	mesoporous SnO ₂ agglomerates	200-600 nm	molten salt method	8 μ m	3.05	TiCl ₄ /6.23
11	SnO ₂ nanofibers	200 nm	---	8.7 μ m	--	TiCl ₄ /4.63
Our work	Ga-SnO₂hollow microspheres	11.6-15.9 nm	hydrothermal	8 μm	3.56	TiCl₄/7.11

^asurface treatment method and the corresponding photon-to-electron conversion efficiency.

Table S2. Calculated structural parameters a and c for pure SnO₂ and 6.25% Ga doped

SnO₂.

	Experiment for SnO ₂	Calculation for SnO ₂	Calculation for Sn _{0.9375} Ga _{0.0625} O ₂	Calculation for 6.25% Ga interstitial doping
a (Å)	4.74 ^b	4.76	4.75	4.81
c (Å)	3.19 ^b	3.21	3.20	3.22

^bPhys. Rev. B. 81, 245216, 2010

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